

PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Venkat Selvamanickam, et al.

Title: METALORGANIC CHEMICAL VAPOR DEPOSITION (MOCVD)  
PROCESS AND APPARATUS TO PRODUCE MULTI-LAYER HIGH-  
TEMPERATURE SUPERCONDUCTING (HTS) COATED TAPERECEIVED  
CENTRAL FAX CENTER  
FEB 21 2006

App. No.: 10/602,468

Filed: June 23, 2003

Examiner: Jennifer C. McNeil

Group Art Unit: 1775

Customer No.: 34456

Confirmation No.: 2661

Atty. Dkt. No.: 1014-SP156-US

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MS AF  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

## RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

In response to the Final Office Action mailed October 18, 2005, reconsideration and withdrawal of the rejections contained therein are respectfully requested for the following reasons.

CERTIFICATE OF TRANSMISSION/MAILING	
I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to the Commissioner for Patents on <u>02/21/2006</u>	
<u>Elise K. Dougherty</u> Typed or Printed Name	<u>E.K. Dougherty</u> Signature